



AMENDMENT UNDER 37 C.F.R. § 1.116  
EXPEDITED PROSECUTION - GROUP ART UNIT 1762

03500.016291.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
: )  
RYUJI BIRO, ET AL. )  
: )  
Application No.: 10/098,569 )  
: )  
Filed: March 18, 2002 )  
: )  
For: VACUUM DEPOSITION )  
SYSTEM AND THIN-FILM :  
DEPOSITION PROCESS ) June 30, 2004

Examiner: Marianne L. Padgett

Group Art Unit: 1762

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

a) Introductory Comments

In response to the final Office Action dated April 1, 2004, kindly amend the  
subject application under 37 C.F.R. § 1.116 as follows:

IFW  
AF/1762

Entered by  
RCE  
8/9/04  
RCE

Do not enter - Mr. Padgett 7/26/04